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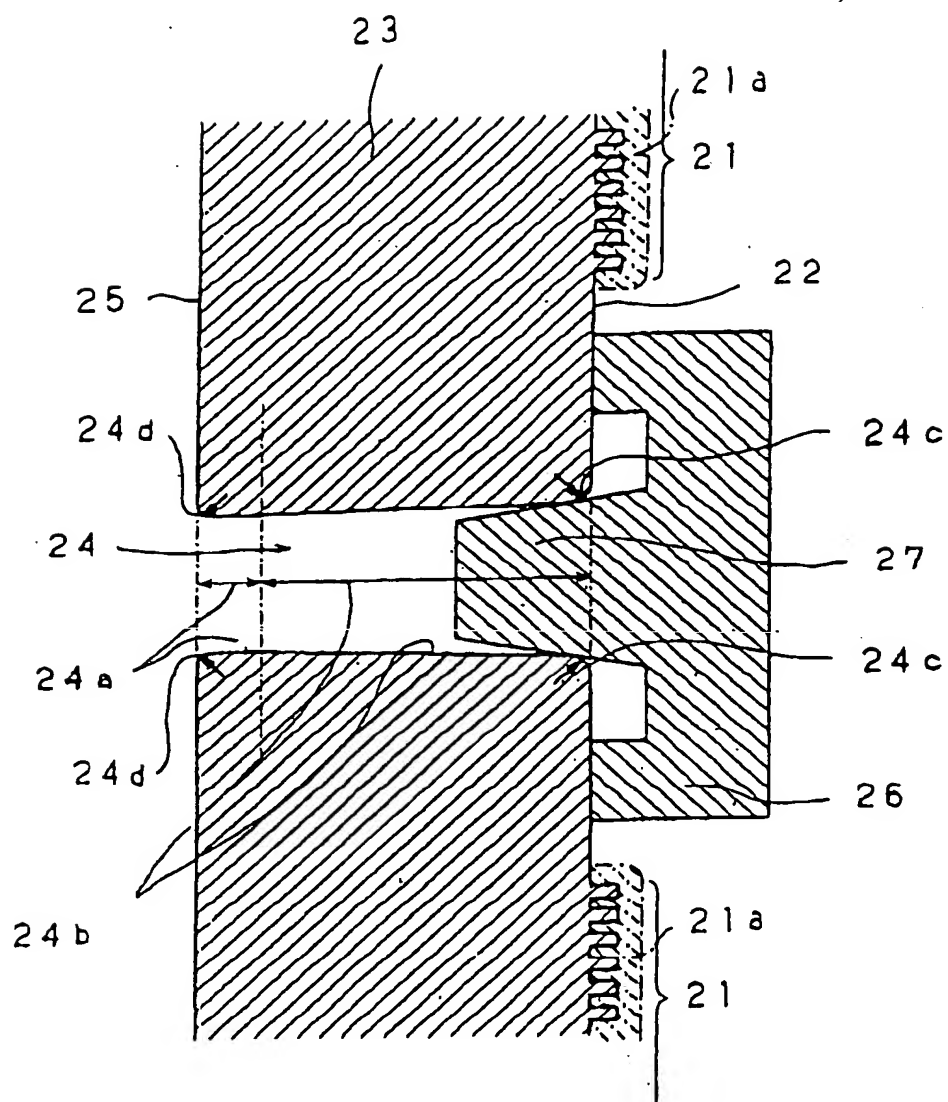


Fig.1

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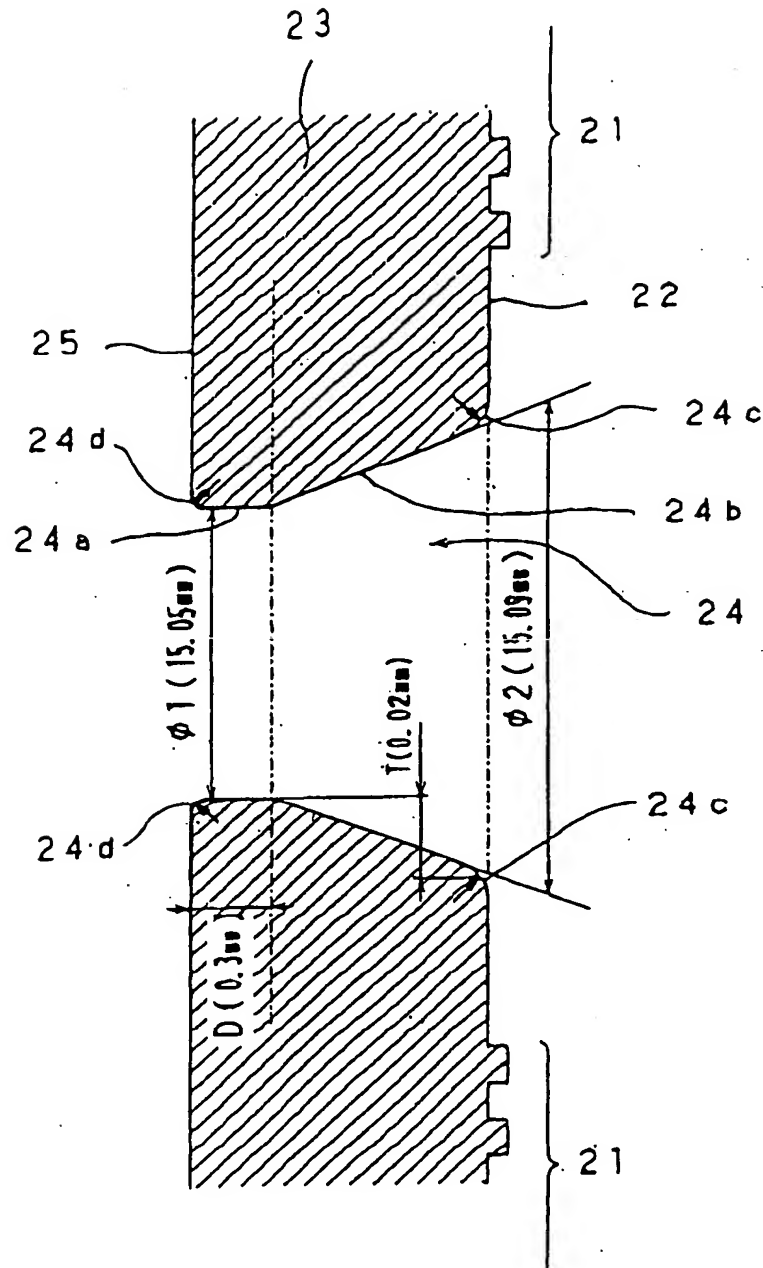


Fig.2

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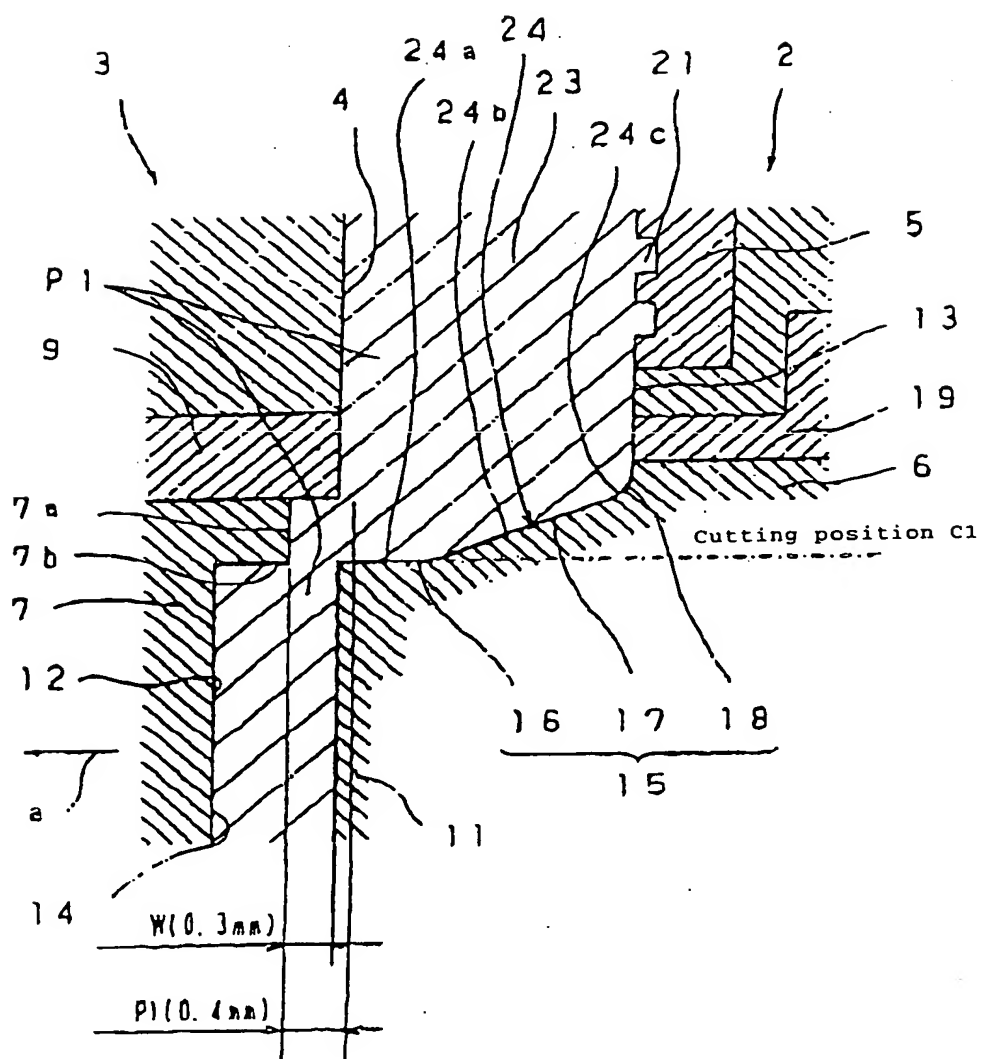


Fig.3

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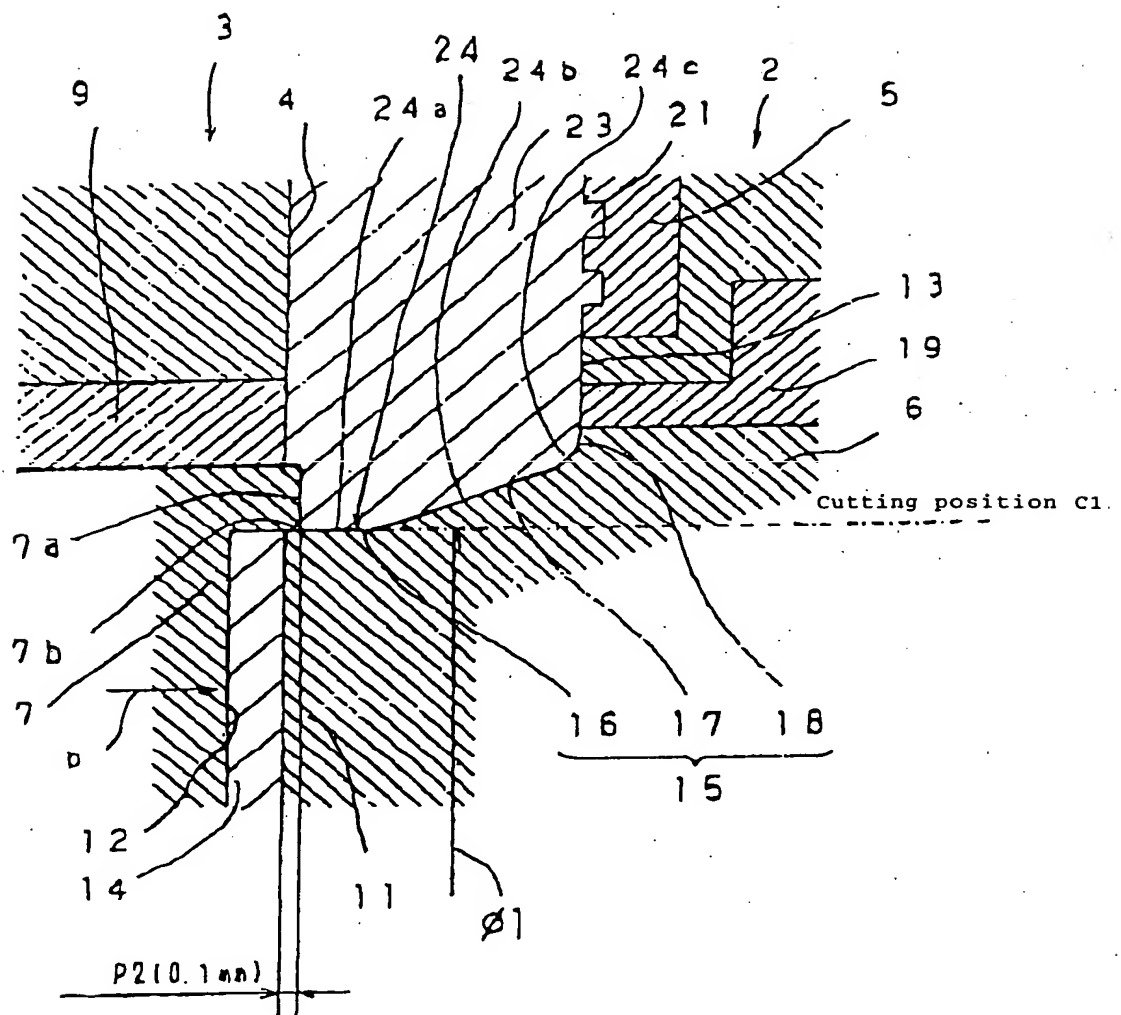


Fig.4

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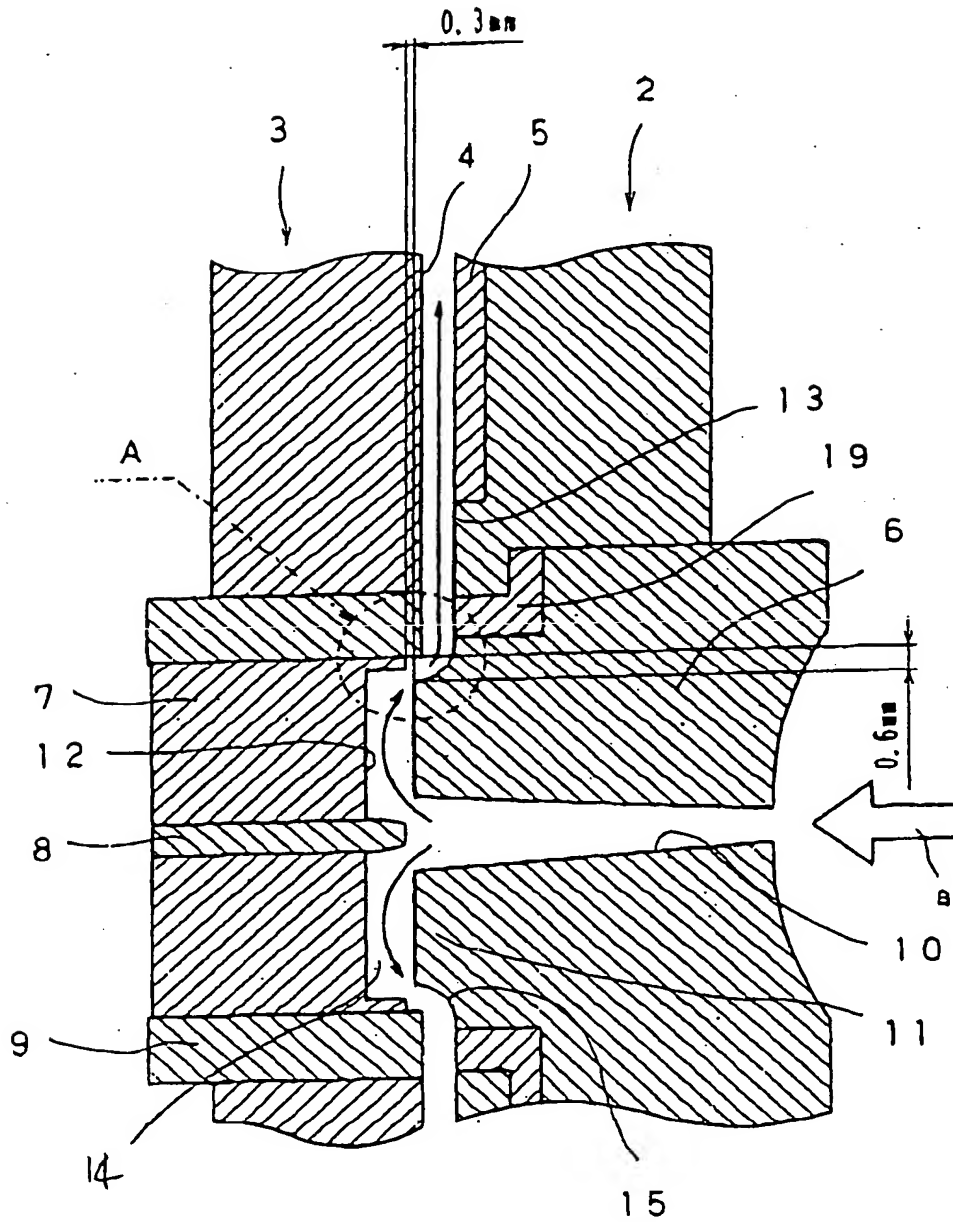


Fig.5

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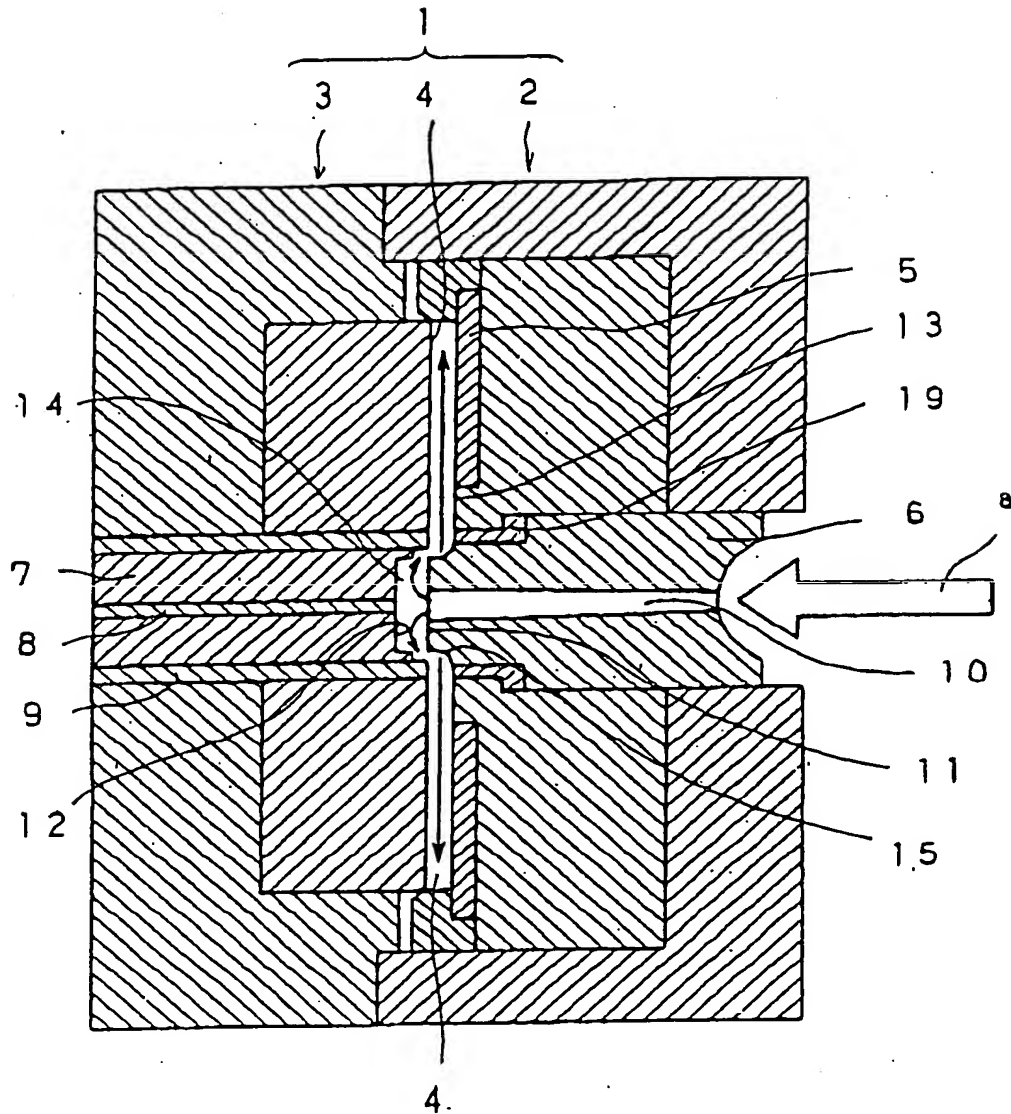


Fig.6

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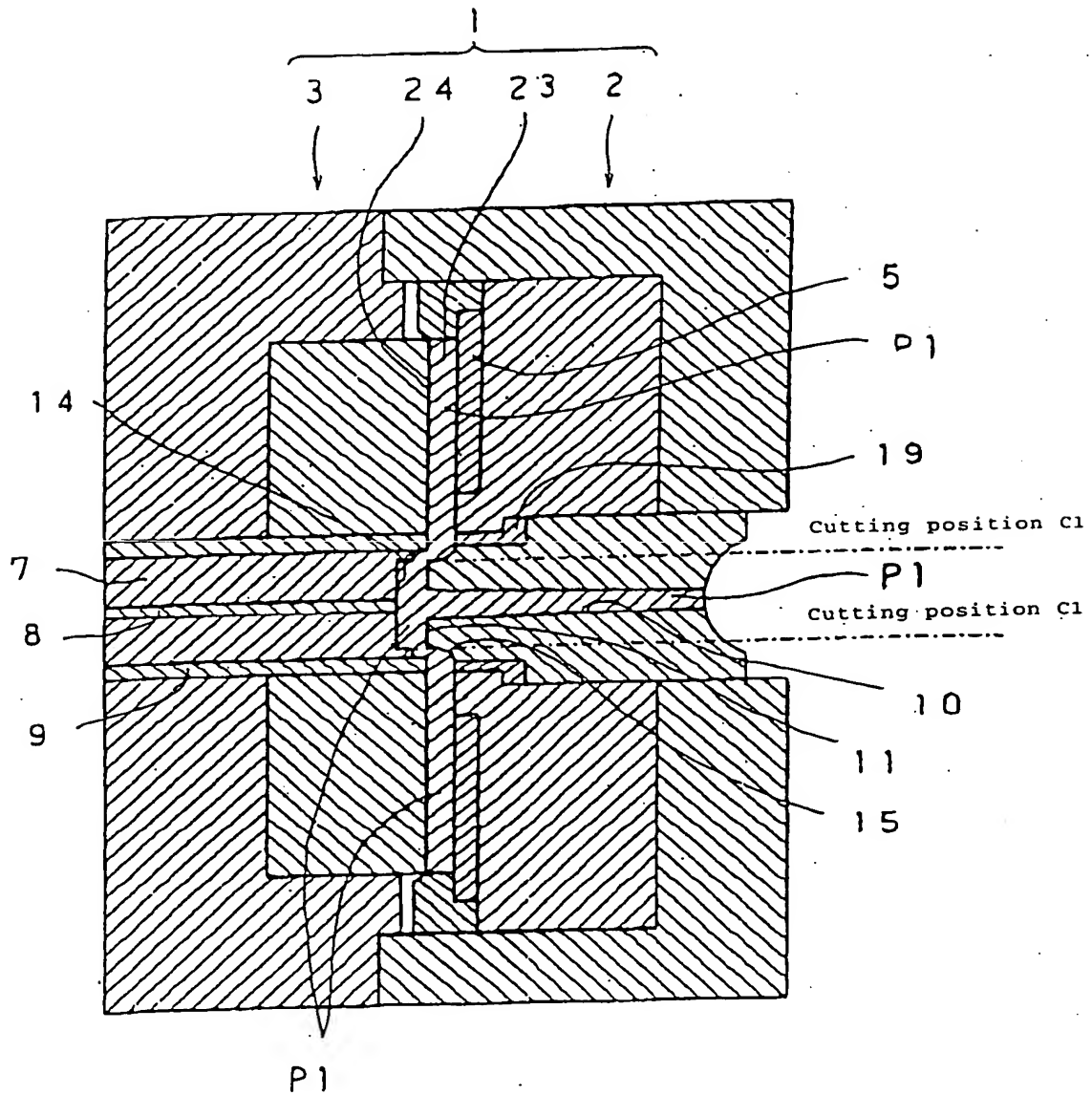


Fig.7

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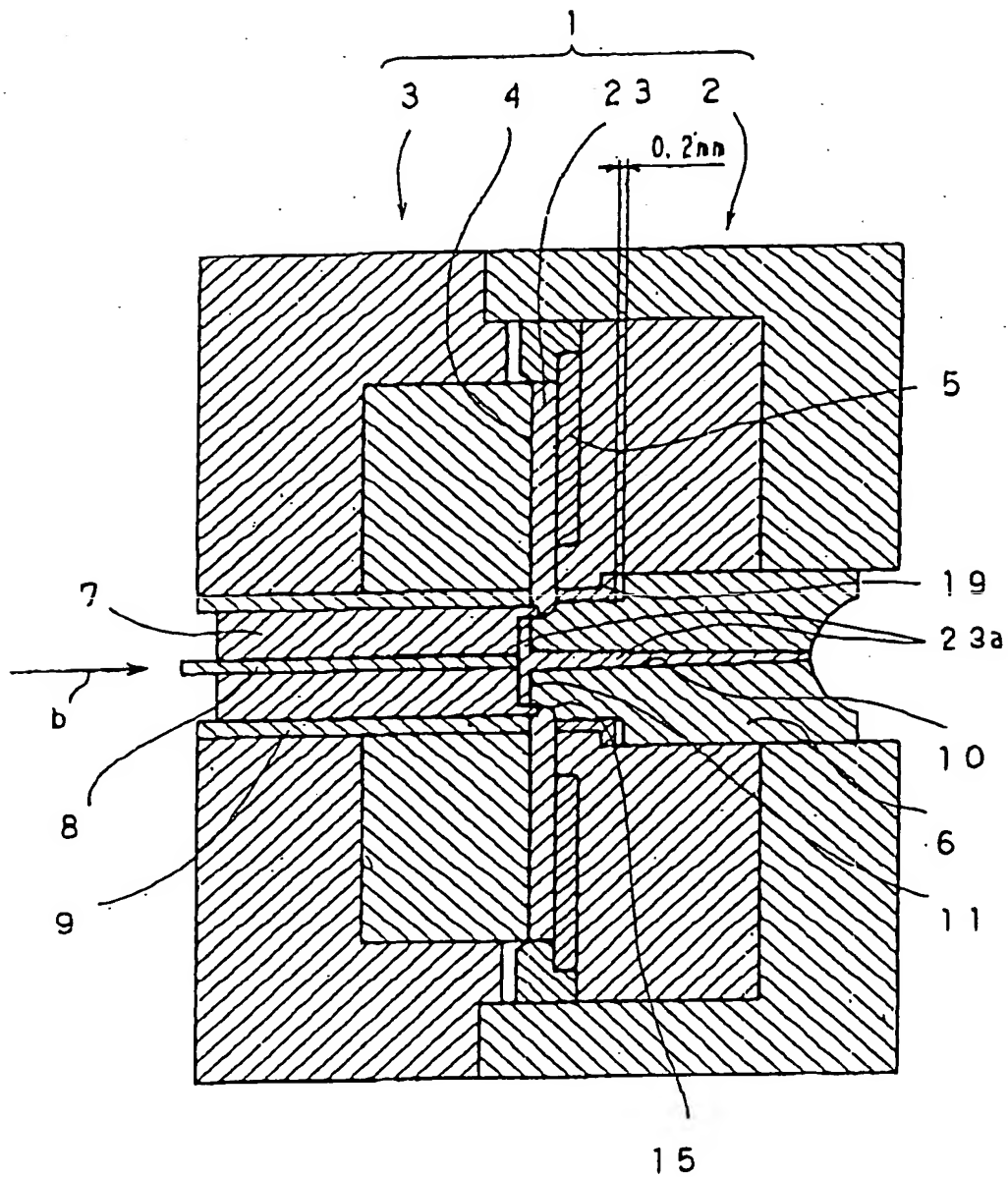


Fig.8

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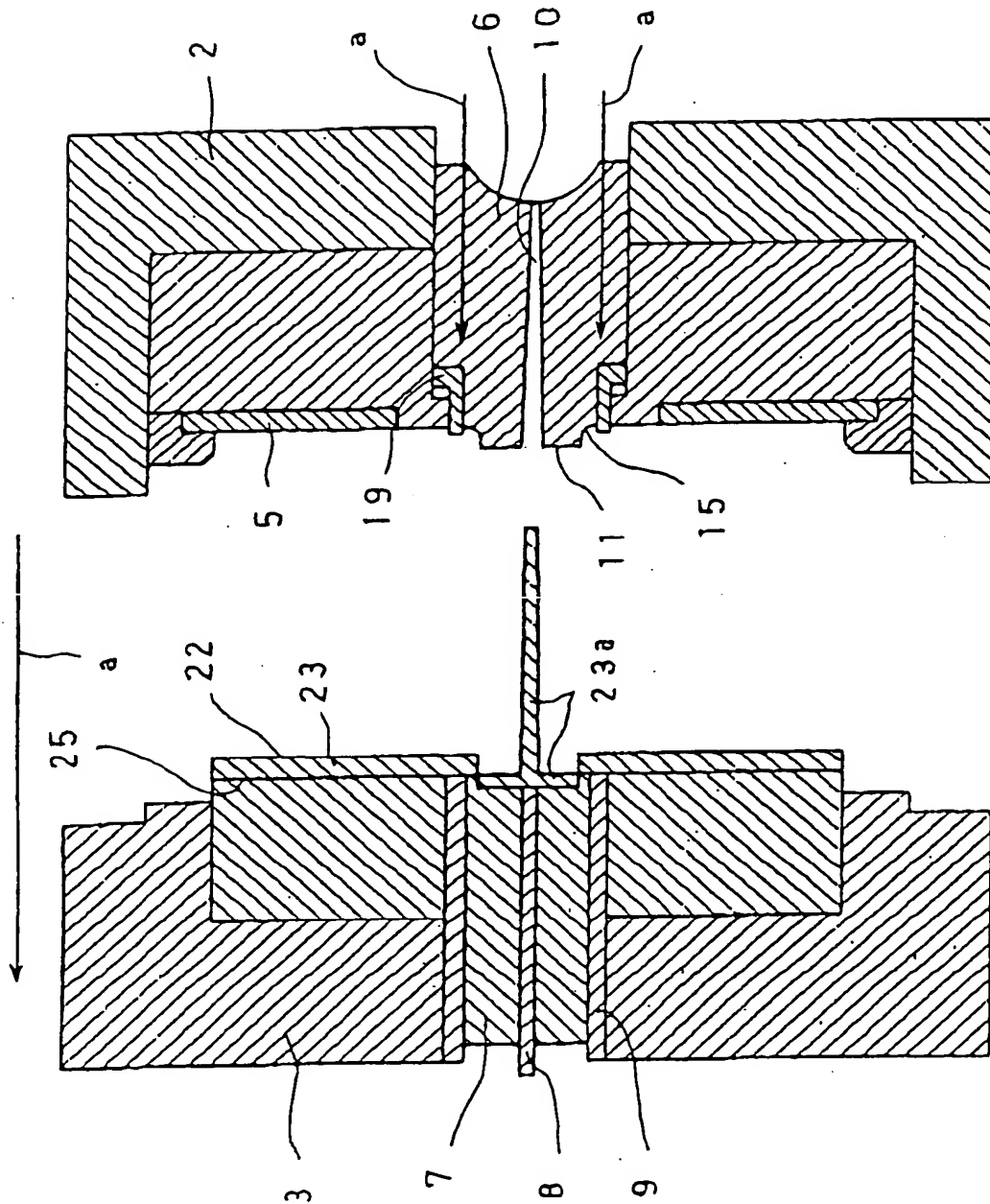


Fig.9

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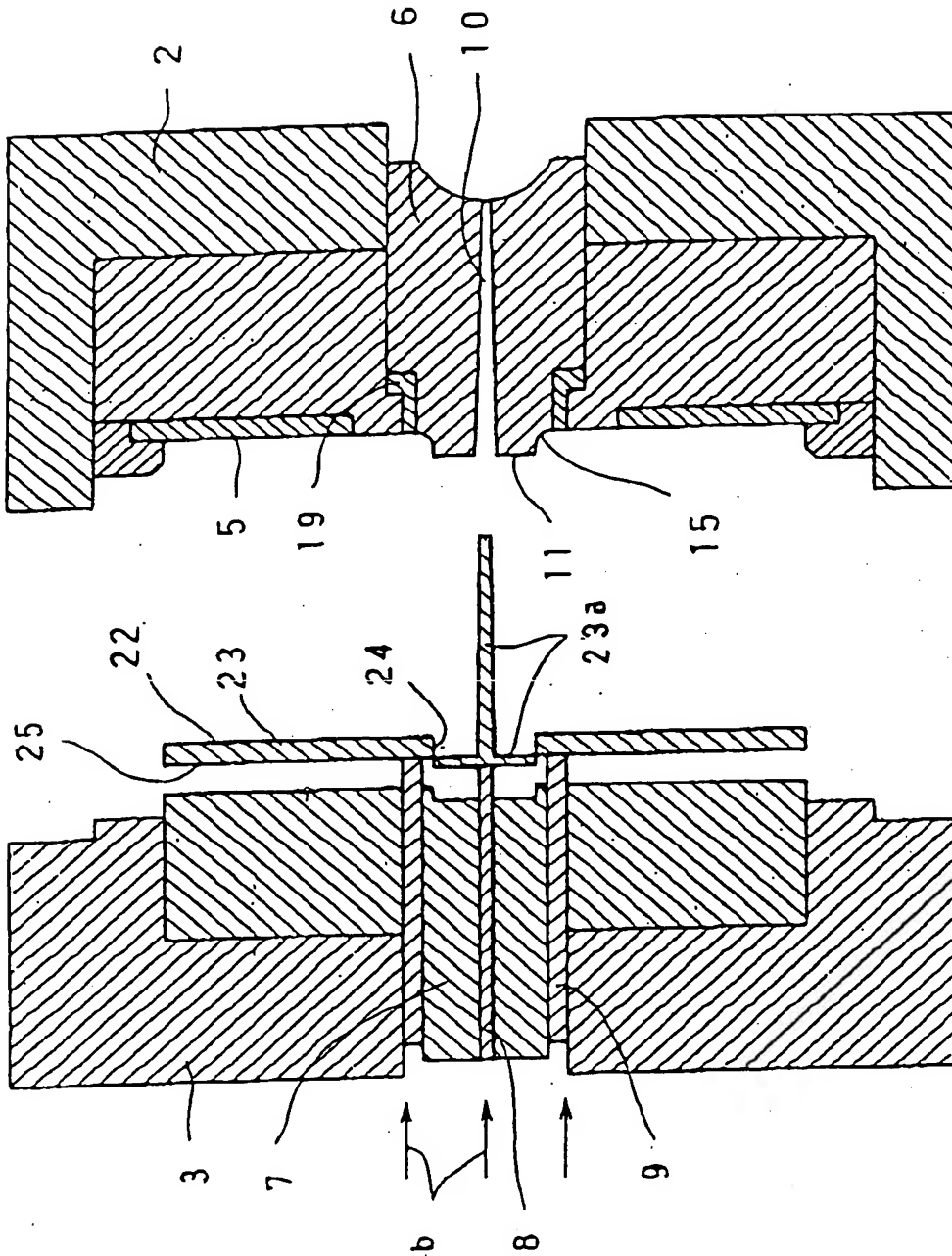


Fig.10

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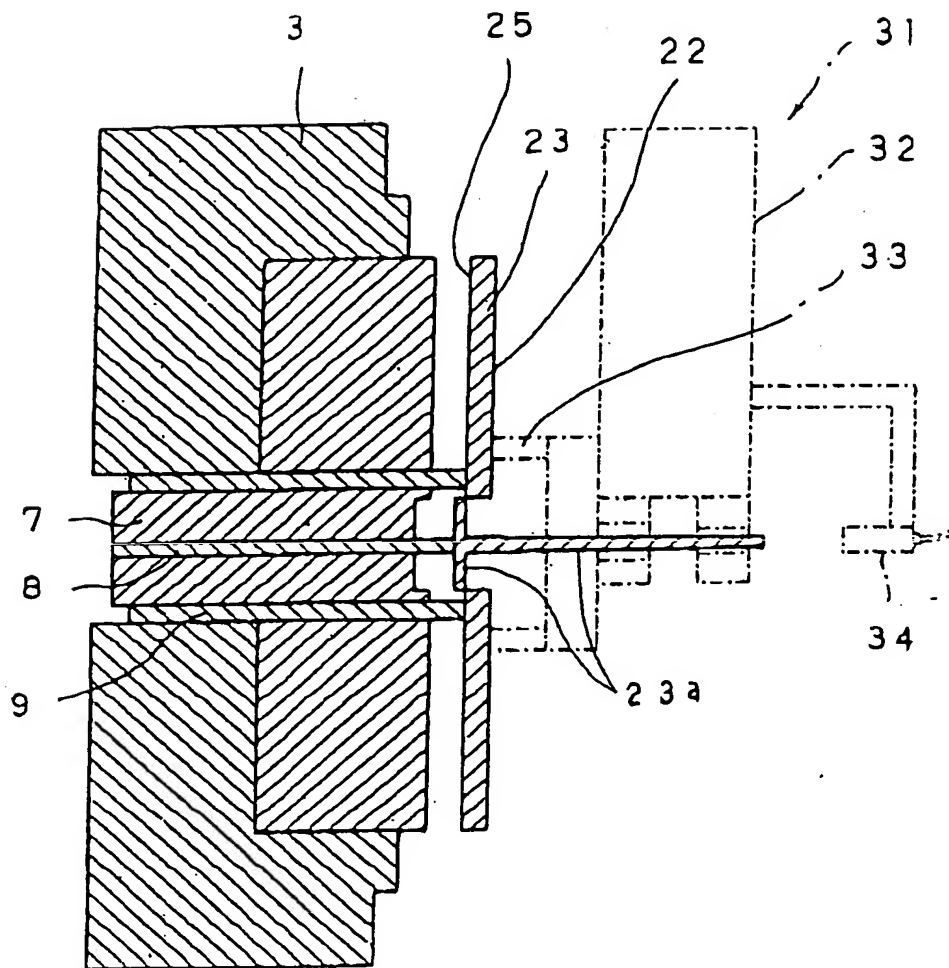


Fig.11

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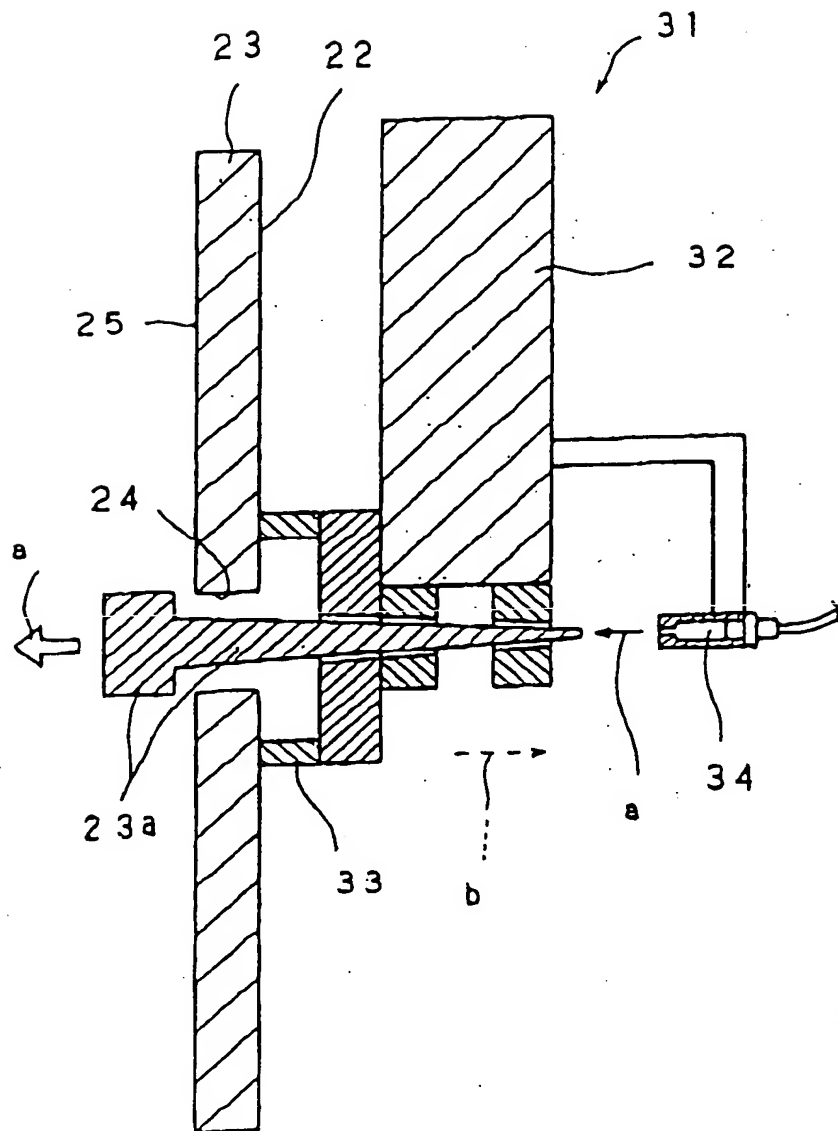


Fig.12

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	Example 1	Comparative Example 1	Comparative Example 2	Comparative Example 3
	Substrate of the present invention	Movable-side stamper substrate	Fixed-side stamper substrate	Comparative Example 2 removed by reamer
Ten measurements of eccentricity amount	20~30 μ m	20~30 μ m	15~70 μ m	20~30 μ m

Fig.13

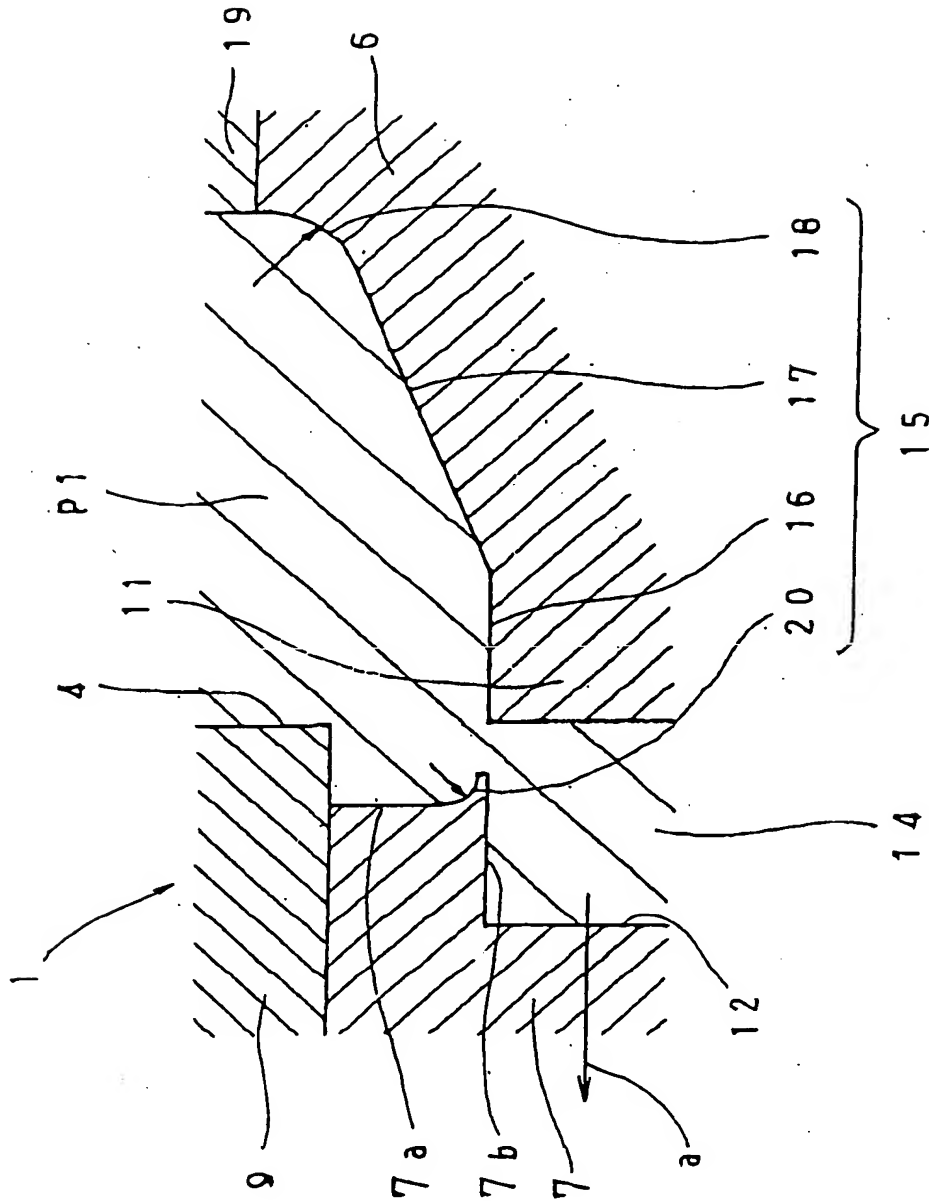
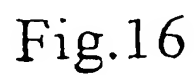


Fig.14

Fig.15



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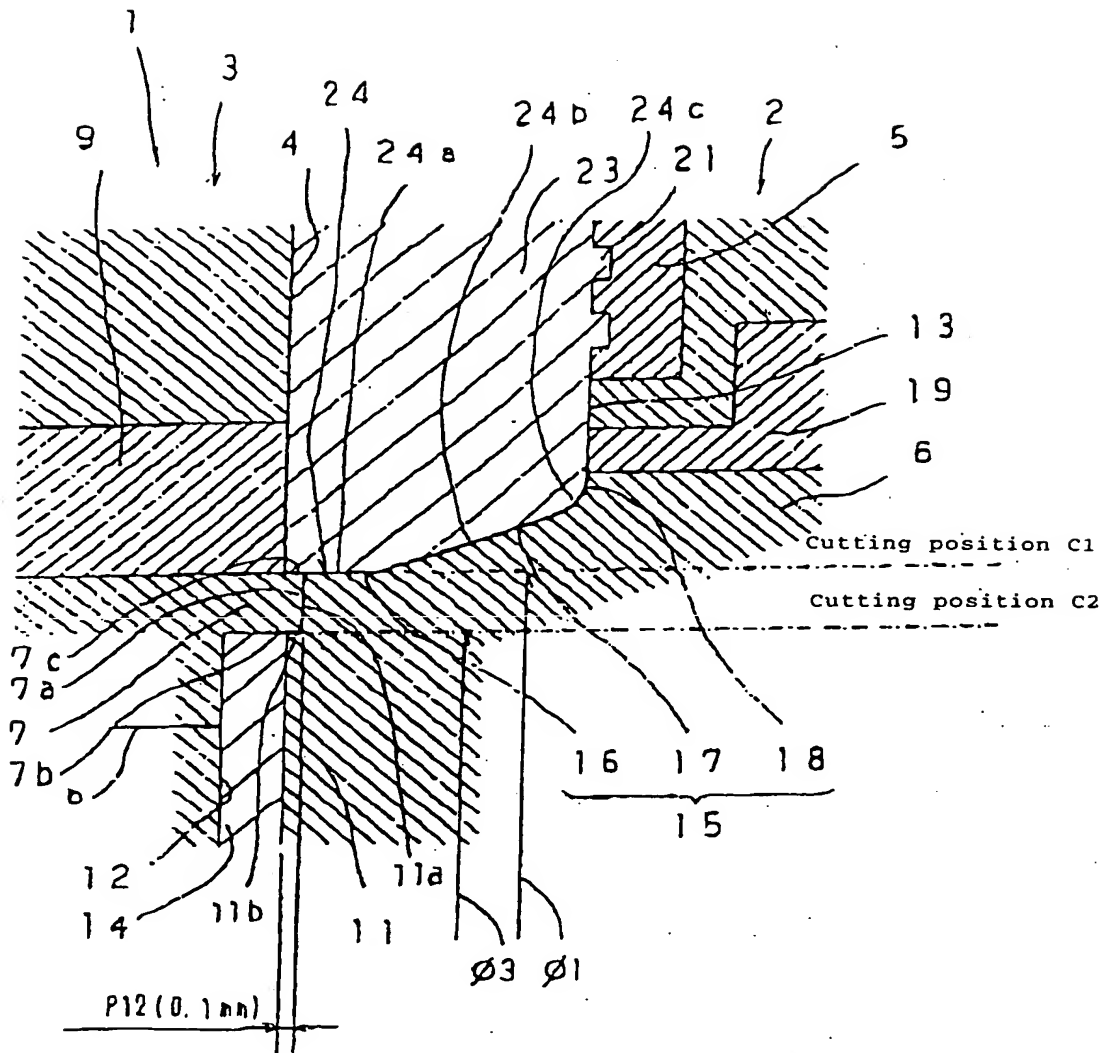


Fig.17

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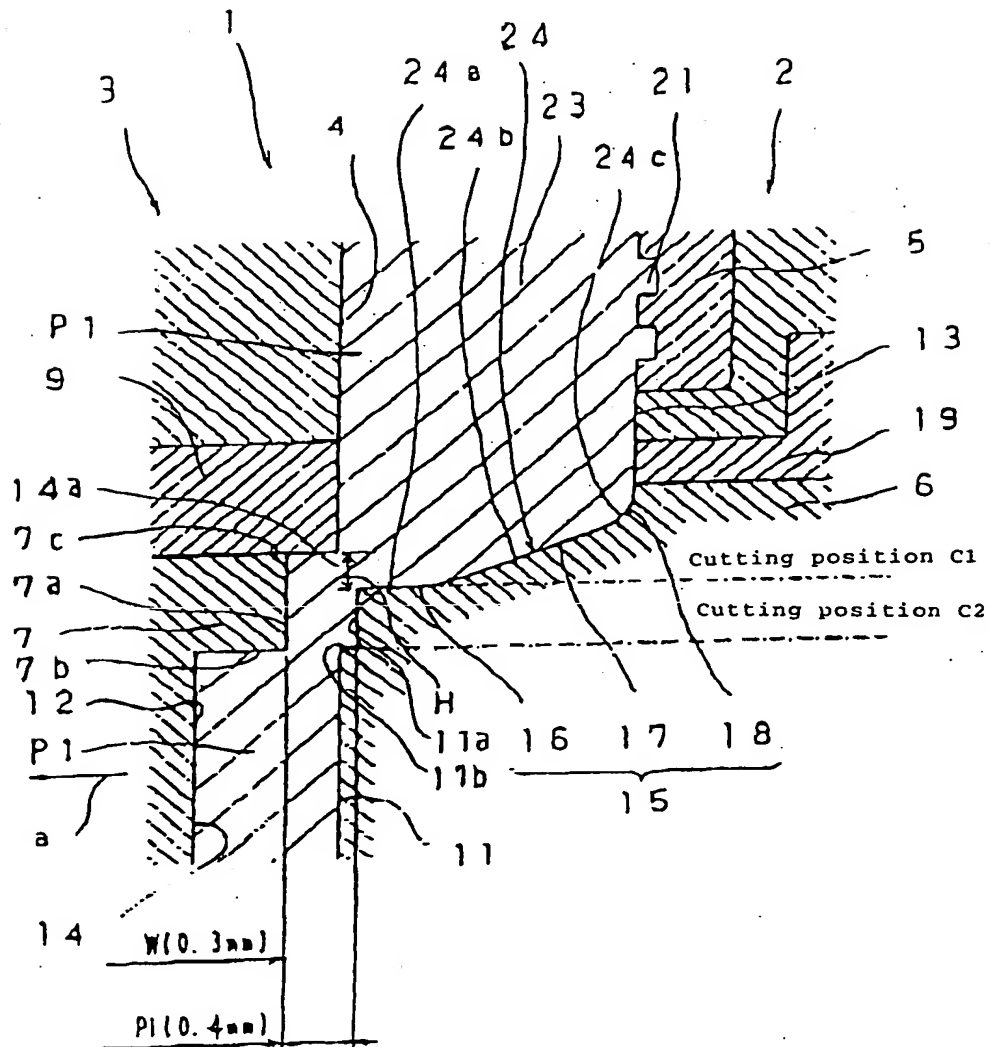


Fig.18

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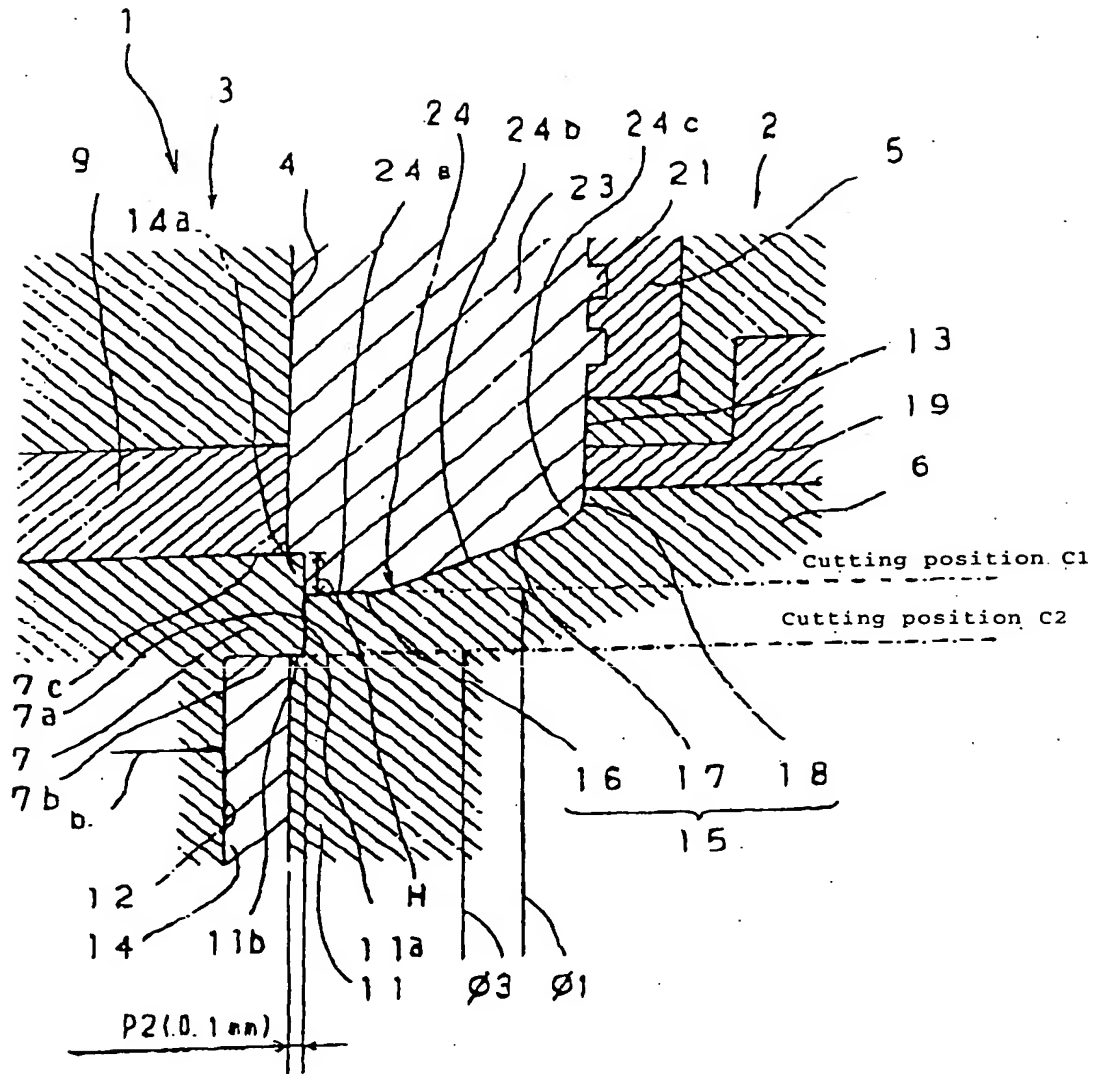


Fig.19

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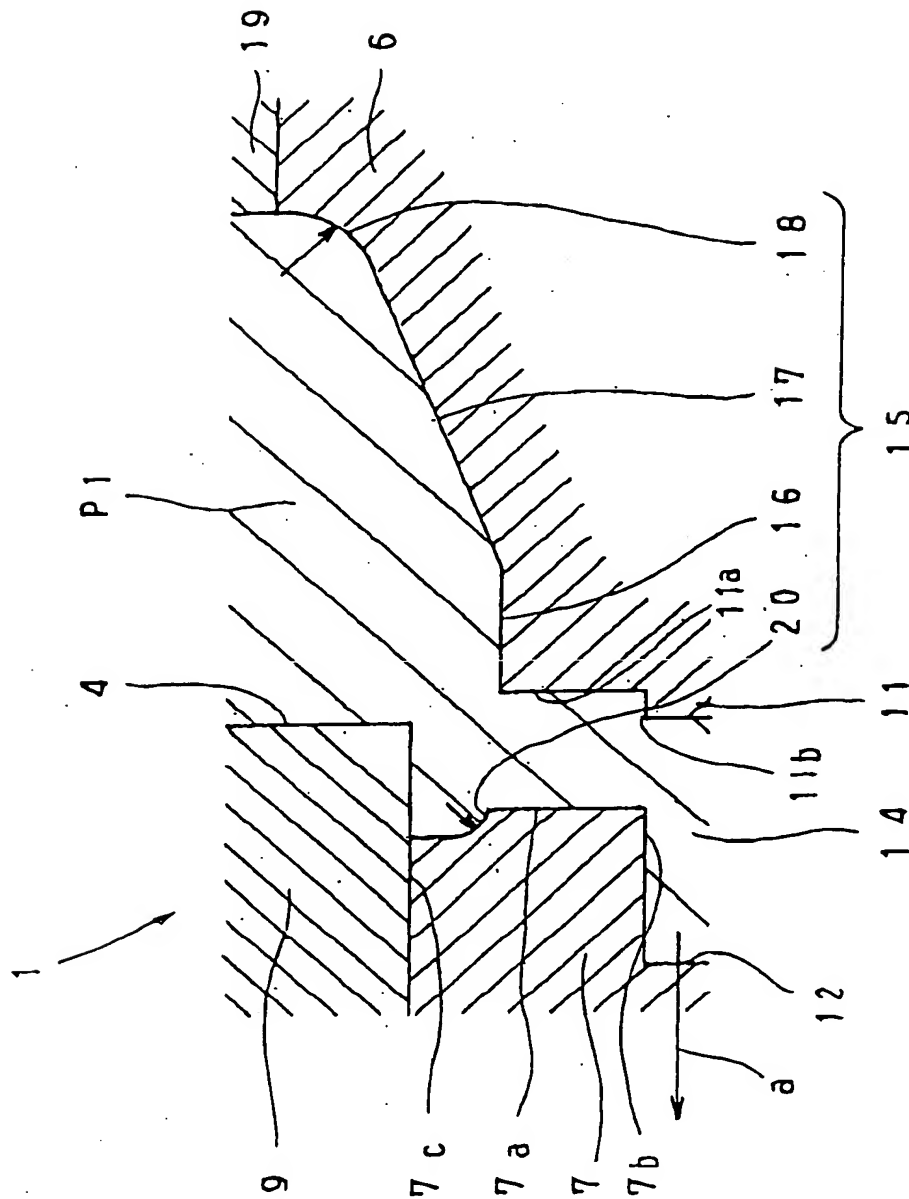


Fig.20

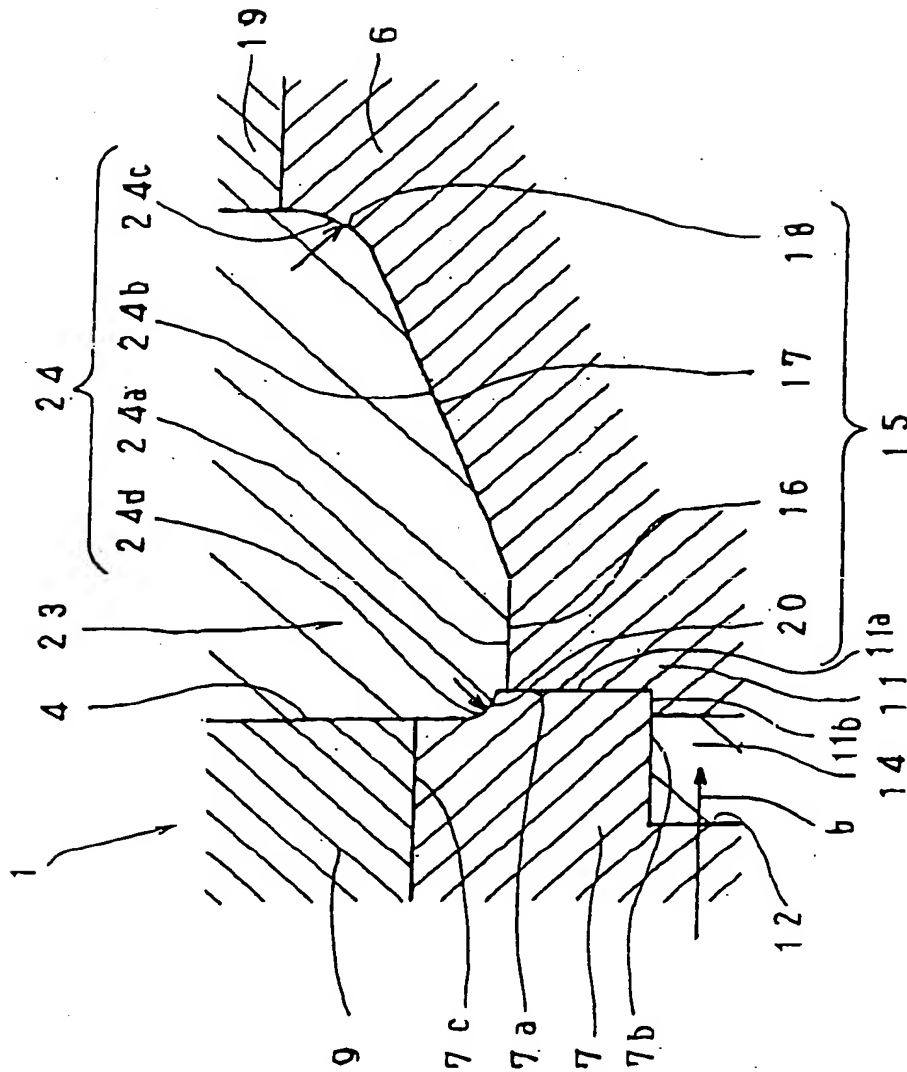


Fig.21

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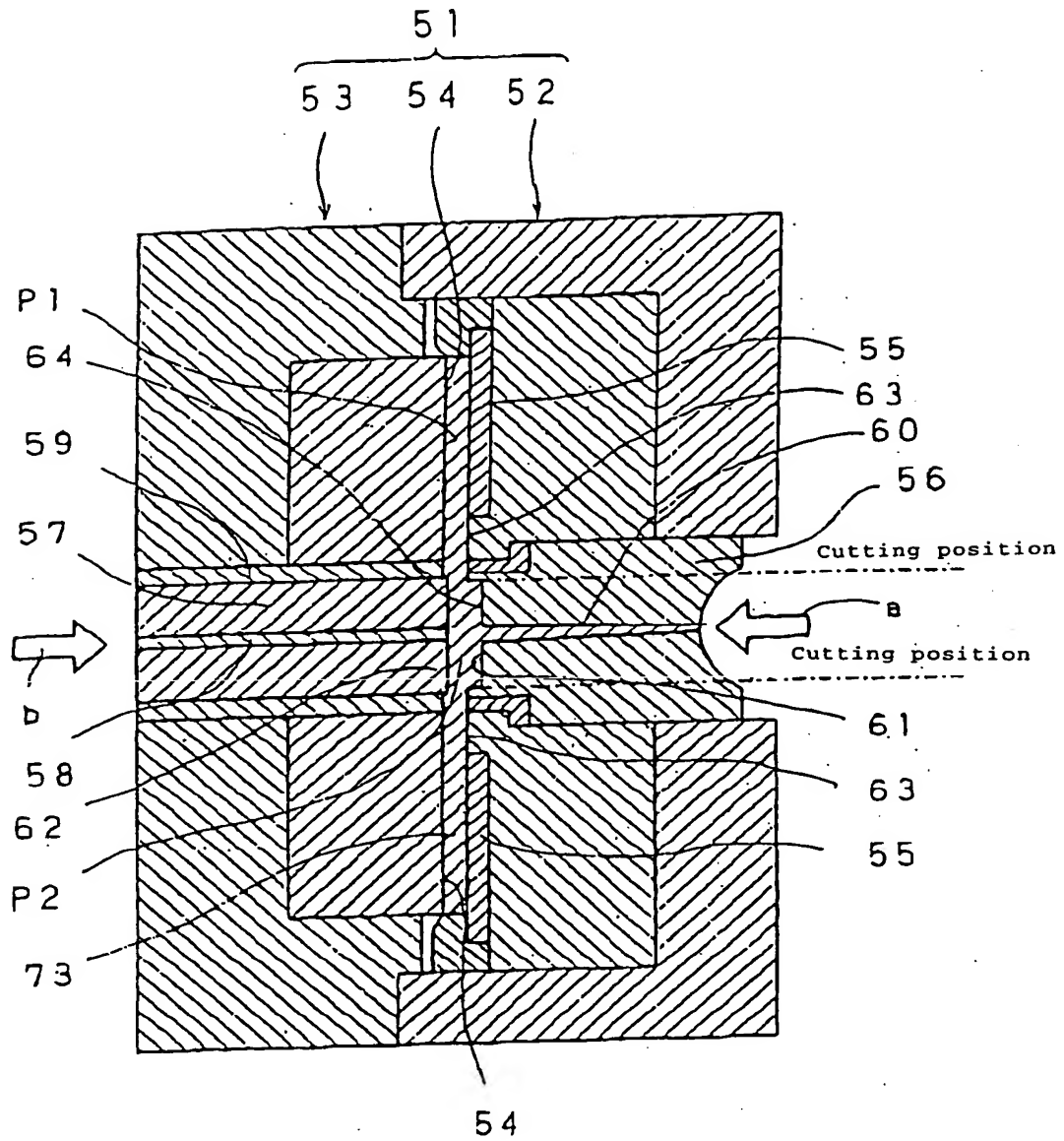


Fig.22

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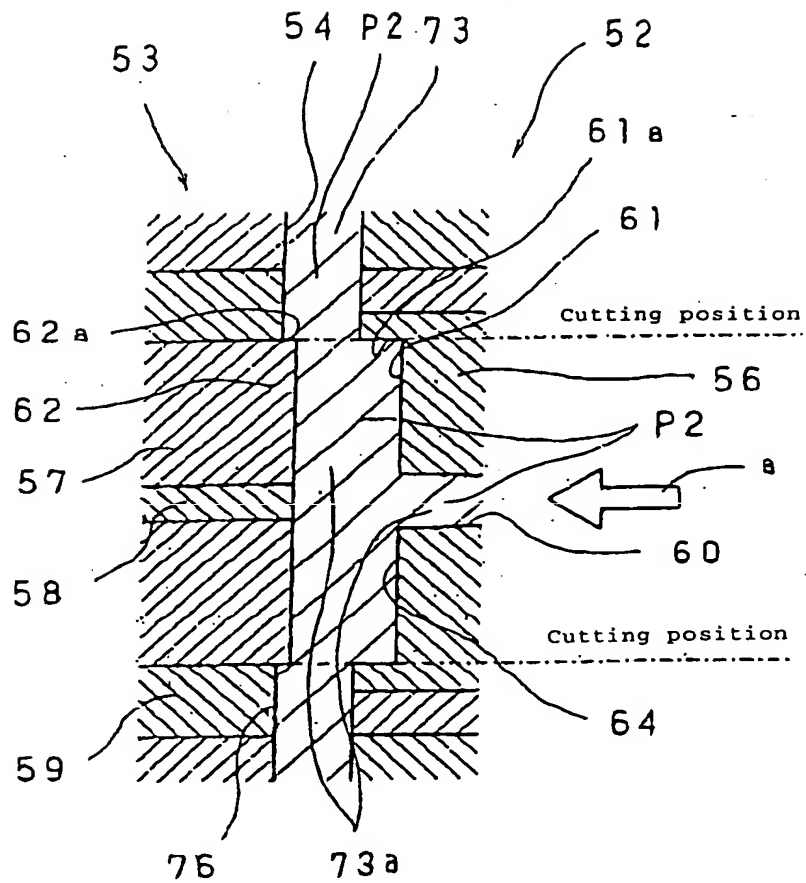


Fig.23

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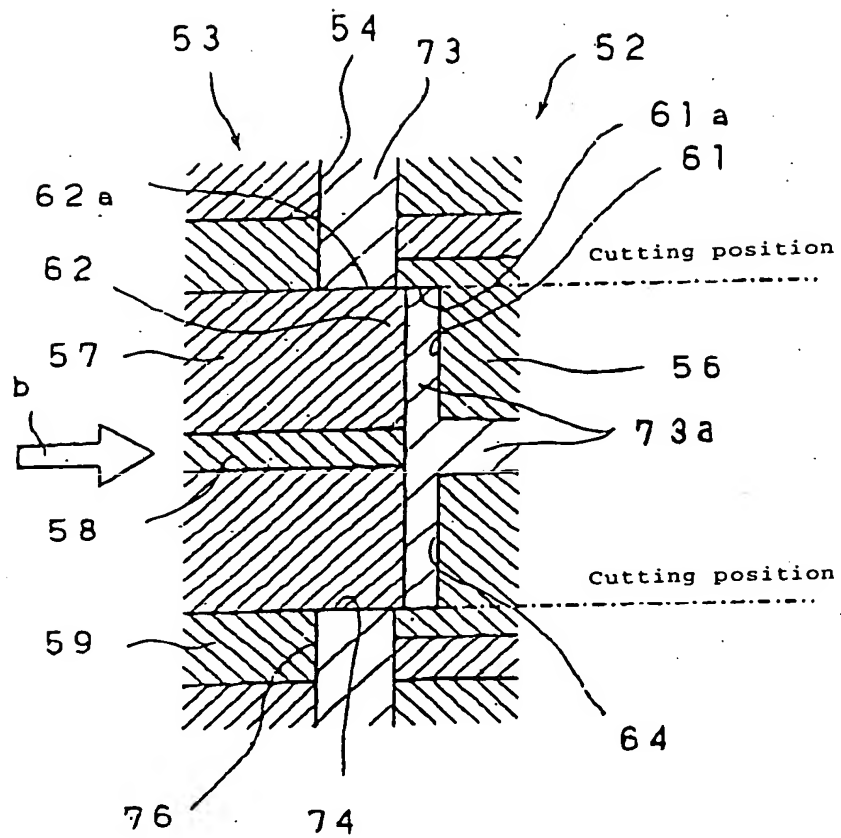


Fig.24

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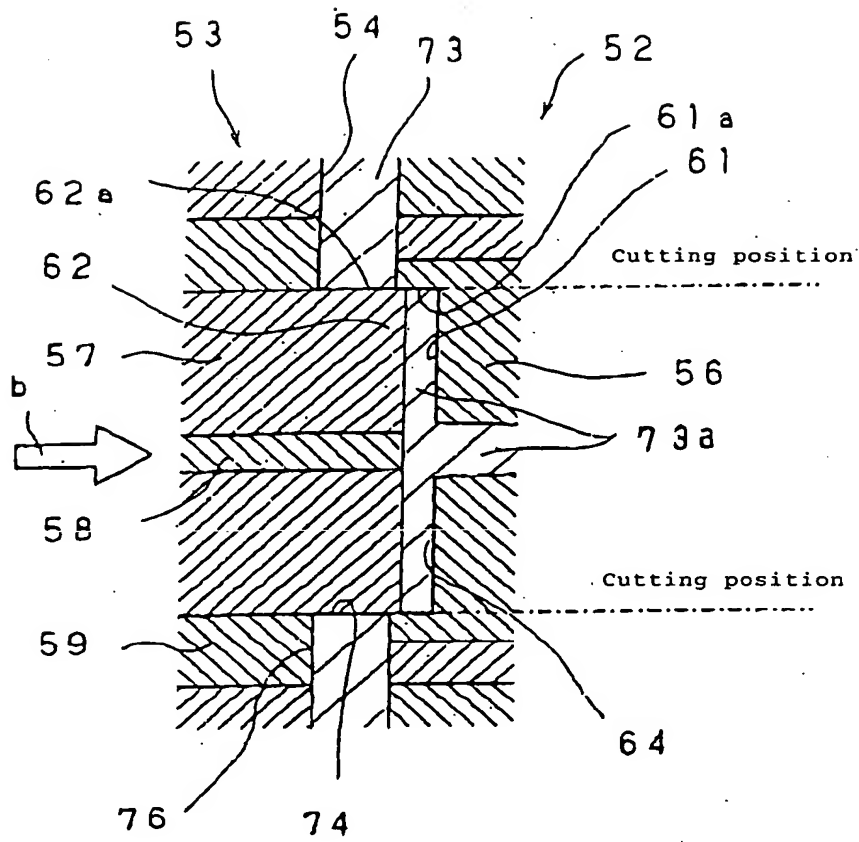


Fig.25

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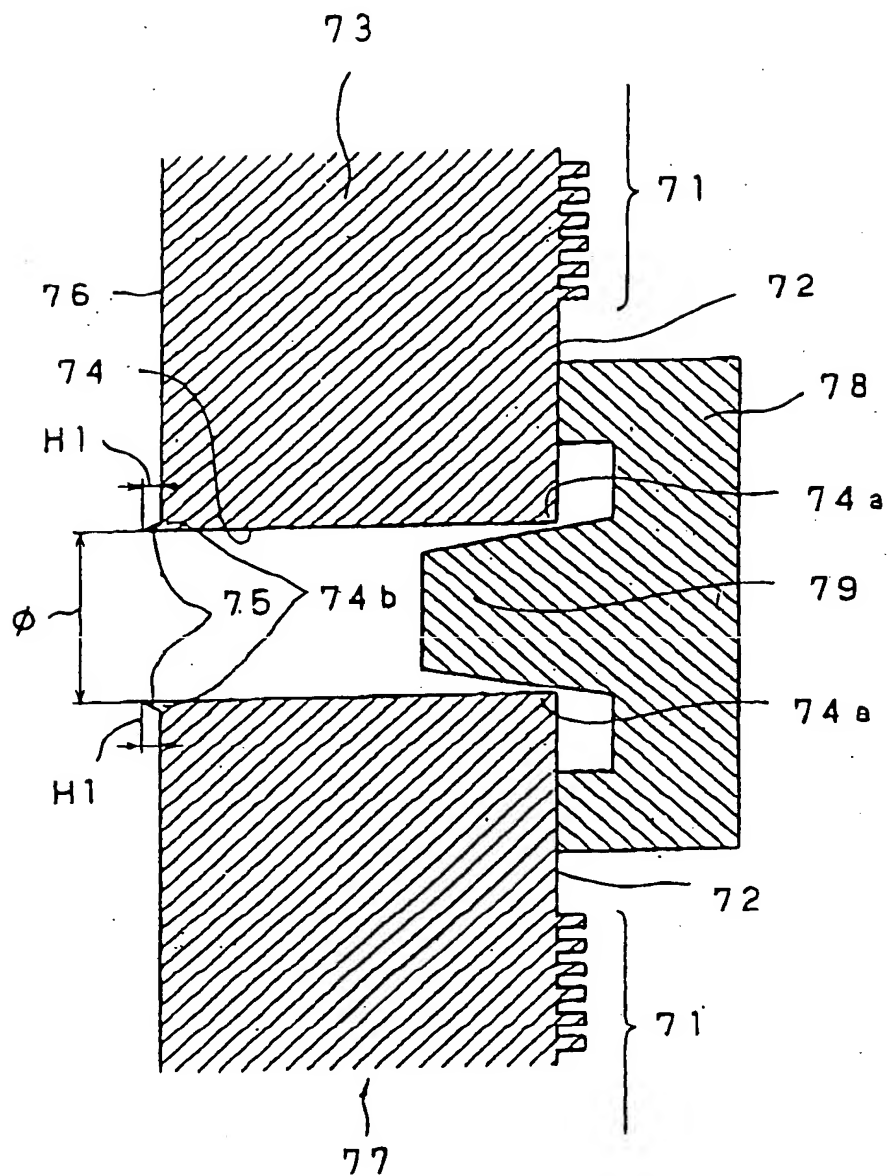


Fig.26

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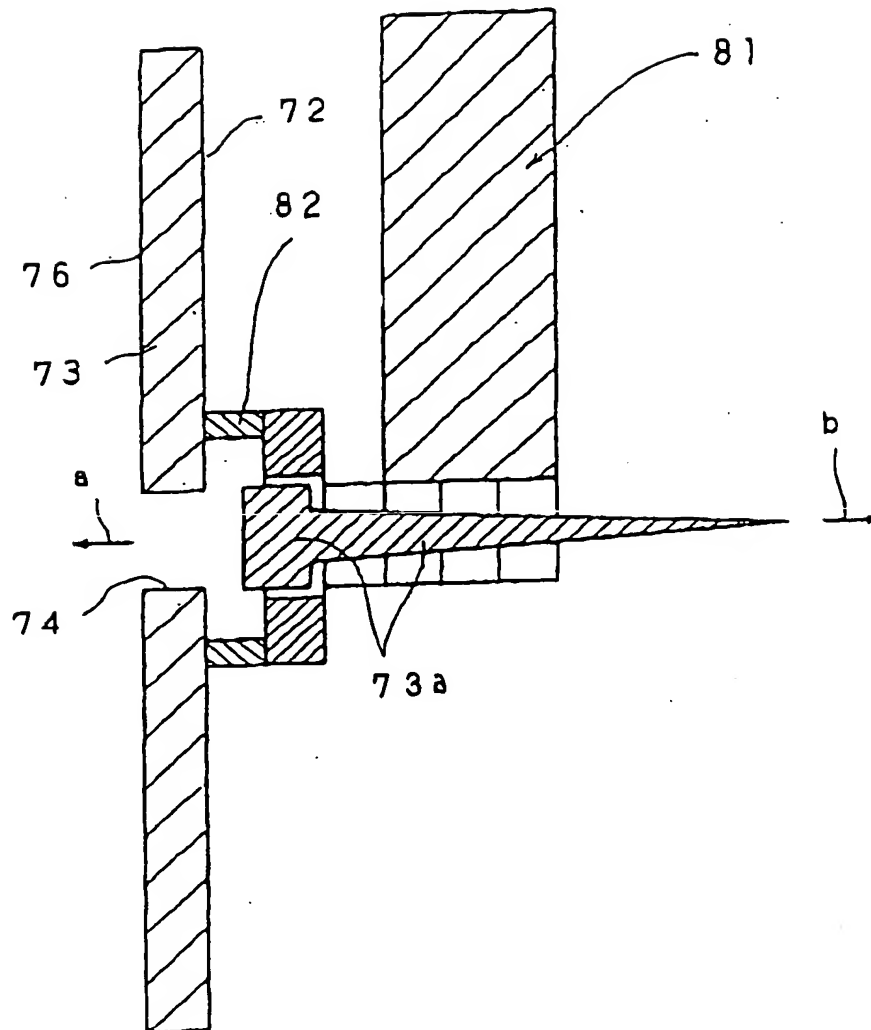


Fig.27